

(12) 按照专利合作条约所公布的国际申请

(19) 世界知识产权组织
国际局

(43) 国际公布日
2025 年 6 月 12 日 (12.06.2025)



(10) 国际公布号
WO 2025/118938 A1

- (51) 国际专利分类号:
F27D 1/18 (2006.01) *H01L 21/67* (2006.01)
F27B 1/10 (2006.01) *E05F 5/06* (2006.01)
- (21) 国际申请号: PCT/CN2024/131943
- (22) 国际申请日: 2024 年 11 月 14 日 (14.11.2024)
- (25) 申请语言: 中文
- (26) 公布语言: 中文
- (30) 优先权:
202311675317.0 2023 年 12 月 7 日 (07.12.2023) CN
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(54) Title: FURNACE DOOR DRIVING DEVICE AND SEMICONDUCTOR HEAT TREATMENT APPARATUS

(54) 发明名称: 炉门驱动装置及半导体热处理设备

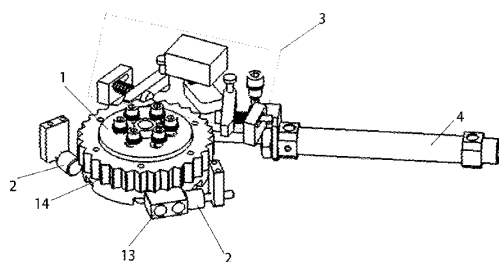


图 1

(57) Abstract: A furnace door driving device and a semiconductor heat treatment apparatus. The furnace door driving device comprises a connecting disc (1), a limiting assembly (2), a stop assembly (3) and a driving source (4), wherein the driving source (4) is used for driving the connecting disc (1) to rotate around the axis thereof; the connecting disc (1) is connected to a furnace door (02) and used for driving the furnace door (02) to rotate; the connecting disc (1) is provided with a limiting portion (13) and a stop portion (14); the limiting assembly (2) is used for limiting fitting with the limiting portion (13) when the connecting disc (1) rotates to a preset limiting position, thus making the connecting disc (1) stop rotating in the original rotation direction; and the stop assembly (3) is used for stop fitting with the stop portion (14) when the limiting assembly (2) is in limiting fitting with the limiting portion (13), preventing the connecting disc (1) from rotating in a direction opposite to the original rotation direction. Thus, the furnace door (02) is prevented from rotating in the opposite direction, avoiding vigorous vibration of the connecting disc (1) due to repeated limiting fitting between the connecting disc (1) and the limiting assembly (2), and thereby avoiding damage to the furnace door (02) caused by excessive vibration.

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本国际公布:

— 包括国际检索报告(条约第21条(3))。

(57) 摘要: 一种炉门驱动装置以及半导体热处理设备。其中, 炉门驱动装置包括连接盘(1)、限位组件(2)、止动组件(3)以及驱动源(4); 驱动源(4)用于驱动连接盘(1)绕自身轴线旋转; 连接盘(1)与炉门(02)连接, 用以带动炉门(02)旋转; 连接盘(1)具有限位部(13)和止动部(14); 限位组件(2)用于在连接盘(1)旋转至预设限位位置时与限位部(13)限位配合, 以使连接盘(1)停止沿原旋转方向继续旋转; 止动组件(3)用于在限位组件(2)与限位部(13)限位配合时, 与止动部(14)止动配合, 以阻止连接盘(1)沿与原旋转方向相反的方向旋转, 从而阻止炉门(02)反向旋转, 并避免连接盘(1)与限位组件(2)之间反复进行限位配合而导致连接盘(1)产生剧烈振动, 进而避免炉门(02)因发生过大的振动而损坏。